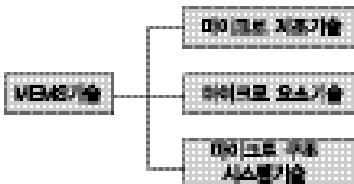


MEMS Micro Electro Mechanical Systems

MEMS
MEMS
(Micro System Technologies : MST) 가 .

MEMS Micro Opto Electro Mechanical System(MOEMS)

MEMS



MEMS

- 20

MEMS

- MEMS

가 5 20

1~2

가

- 20

MEMS

(bio-compatible)

MEMS

MEMS

MEMS

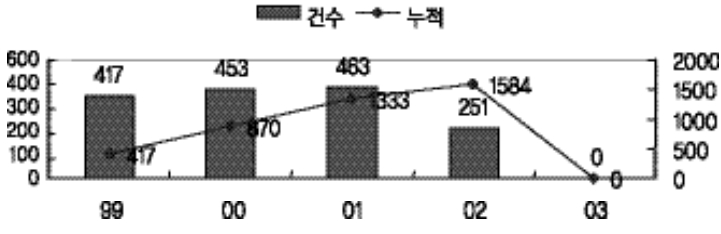
[1] “

5

2] 10

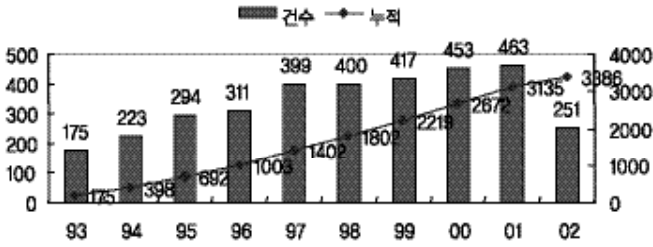
”

, [



[1] (5)

[3]
가
. 2001



[2] (10)

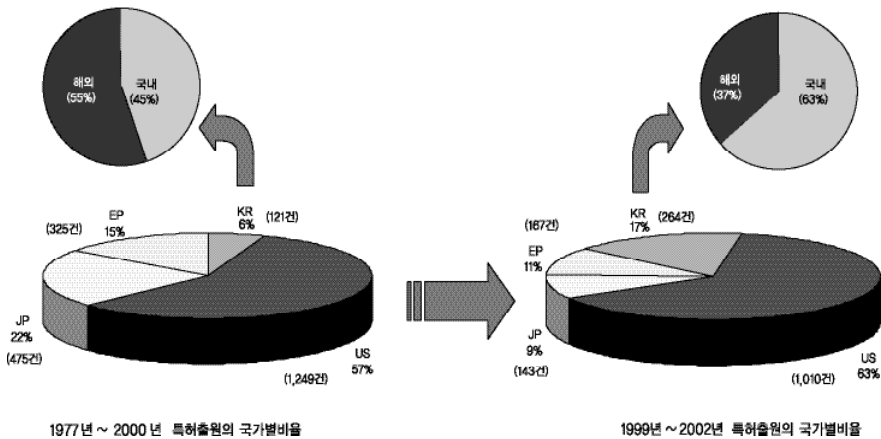
2
. 1977~2000

가
가
. 2003
0
가

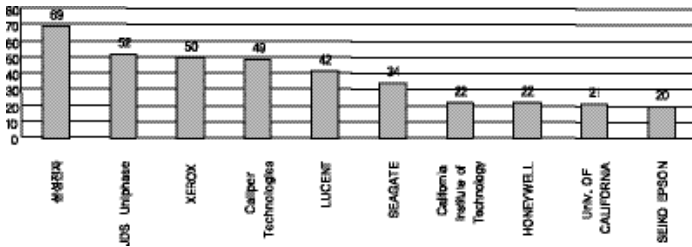
1999~2000

55%
5
97 37%

가



[3] 가 (:)



[4] (10)

, JDS Uniphase,
Xerox, LUCENT “
”
가
SEIKO Epson,
California , HONEYWELL



[5] (10)

Caliper Technology
“ ”
“ ”
HONEYWELL “
”
. 10
1977
20

[6] “ ”

[4] 10
1,584
가 439
28%

5
4 83
(131)

가 49 71% “ ”
가 15 “ 가 5

330 44 13%
가 5 가
, KAIST ETRI가 12 9

[5] 10

- MEMS , 가

